

Reply under 37 C.F.R. 1.116
Expedited Procedure
Technology Center 1792

Confirmation no. 3423

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	DE BOER	Examiner:	Lund, J.
Serial No.:	10/537,363	Group Art Unit:	1792
Filed:	June 2, 2005	Docket No.:	US020527US (NXPS.441PA)
Title:	SYSTEM AND METHOD FOR SUPPRESSION OF WAFER TEMPERATURE DRIFT IN COLD-WALL CVD SYSTEMS		

AMENDMENT AND REQUEST FOR CONTINUED EXAMINATION

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Customer No. 65913

Dear Sir:

In response to the Final Office Action dated January 27, 2010, please consider the following response.

A complete listing of the Claims and Remarks/Arguments follow.

Authorization is given to charge/credit **Deposit Account 50-4019 (US020527US)** all required fees/overages to enter this paper.